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SHIMIZU MASAOKI(54) MANUFACTURING METHOD OF CARBON NANOTUBE AND/OR FULLERENE AND  
MANUFACTURING DEVICE THEREFOR

## (57)Abstract:

PROBLEM TO BE SOLVED: To provide a manufacturing method and manufacturing device capable of continuously manufacturing high purity nanotube and/or fullerene with high production efficiency.

SOLUTION: The manufacturing method of carbon nanotube or the like is performed by reducing the pressure in a system to  $\leq 1.3$  Pa, supplying at least a carbon-containing liquid material, changing the pressure in the system to 1.3-93.3 kPa, discharging arc and supplying the carbon-containing liquid material into the discharge plasma generated by the arc discharge to decompose the carbon-containing liquid material to form carbon nanotube and/or fullerene. At least a pair of electrodes 11a and 11b for generating discharge plasma by the arc discharge is provided in a vacuum chamber 10 and the vacuum chamber 10 is equipped with

a gas supply means 17 capable of supplying a carrier gas and a raw material supply means 16 capable of supplying the carbon-containing liquid material to the discharge plasma through an introducing pipe 15.

